

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: )  
 Y. Gotkis ) Group Art Unit: Unassigned  
 Application No: Unassigned ) Examiner: Unassigned  
 Filed: March 26, 2004 ) Atty. Docket No: LAM2P466  
 For: METHOD AND APPARATUS FOR ) Date: March 26, 2004  
 MEASUREMENT OF THIN FILMS AND RESIDUES ON )  
 SEMICONDUCTOR SUBSTRATES )

CERTIFICATE OF EXPRESS MAILING

I hereby certify that this paper and the documents and/or fees referred to as attached herein are being deposited with the United States Postal Service on **March 26, 2004** in an envelope as "Express Mail Post Office to Addressee" service under 37 CFR §1.10, Mailing Label Number **EV381562815US**, addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Signed: \_\_\_\_\_

Kay Harlow

INFORMATION DISCLOSURE STATEMENT  
UNDER 37 CFR §§1.56 AND 1.97(c)

Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

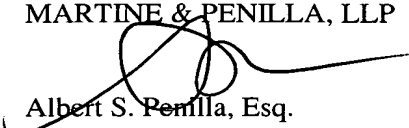
The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicant submits these references in compliance with his duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement (IDS) is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is being filed within three (3) months of the filing date of the above-referenced application. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 50-0805 (Order No. LAM2P466).

Respectfully submitted,

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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Attorney Docket No: U.S. Lam2P466 Applicant: Lam Research Corporation Filing Date: 3/24/2004 Group:

### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class
	A	4,899,055	08/31/1990	Adams	250	372
	B	5,241,366	08/31/1993	Bevis et al.	356	382
	C	6,160,621	12/12/2000	Perry et al.	356	381
	D	6,556,947	04/30/2003	Scheiner et al.	702	172
	E	6,654,108	11/25/2003	Ravid et al.	356	237.2

### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	F	Harland G., Tompkins, <u>A User's Guide to Ellipsometry</u> , 1993, Academic Press, Inc., New York, pg.253-255
	G	Dag et al., "Performing STI process control using large-spot-size Fourier-transform reflectometry" April 2003, MicroMagazine , pgs.25-30
	H	Ouma et al., "Characterization and Modeling of Oxide- Chemical - Mechanical Polishing Using Planarization Length and Pattern Density Concepts" May 2002, IEEE Transactions on Semiconductor Manufacturing Vol 15 No.2
	I	DeJule, Ruth "Advances in Thin Film Measurement" May 1, 1998 Semiconductor Intl.
	J	Tevet, In-Situ Thickness Monitoring System, Aug 2001 <a href="http://www.tevet-pct.com/docs/apcPoster.pdf">http://www.tevet-pct.com/docs/apcPoster.pdf</a>
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered.  
 Include copy of this form with next communication to applicant.